

應用科學研究中心 特邀演講

RCAS Seminar

Seamless wafer-free monolithic 3D integration enabled by confined growth and remote epitaxy

2024

07.19

11:00 - 12:00

Place

B106 Auditorium, 1F,
IRBST, Academia Sinica
跨領域科技研究大樓1F
B106 演講廳

Host

Prof. Yu-Jung Lu
呂宥蓉副研究員



Prof. Jeehwan Kim / Fellow

Massachusetts Institute of Technology
Samsung Advanced Institute of Technology

Contact

Chia-I Chou

E-mail: chiai@gate.sinica.edu.tw
Tel: 02-2787-3103